

## Simulation Study on the Mechanisms of Proton-Induced Single Event Effects in GaN HEMT

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### Abstract

This paper constructs a multi-layer structural model of GaN HEMT based on Geant4 to simulate the distributions of mass number  $A$ , charge number  $Z$ , kinetic energy  $E_k$ , and linear energy transfer (LET) of secondary particles reaching the GaN sensitive layer after 10\$ 500MeV protons incident in the gate, source – gate gap, and drain regions. The results indicate that when 10 200MeV protons are incident on the drain at angles of 0°–60°, the angular effect is smoothed out in the sensitive layer, with deviations in the average  $A$  and  $Z$  less than 10% between angles. This is primarily due to the cumulative attenuation from multiple  $LET(>15\text{ MeV}\cdot\text{cm}^2/\text{mg})$  events increasing from 5% to 15%, representing a 200% increase in the 10\$ 50 MeV range, attributed to the enhanced nuclear reaction yield by high- $Z$  overlayers; the source-gate gap shows intermediate sensitivity with a change rate of 18%; and the drain is the least sensitive, only obvious increase in high-LET interval. These quantitative patterns reveal the microscopic influences of overlayer materials and geometric structures on secondary particle transport, providing a physical basis for explaining threshold issues such as SEGR and SEB.

### Full Text

### Preamble

Simulation Study on the Mechanisms of Proton-Induced Single Event Effects in GaN HEMT\* Li Li,<sup>1</sup> † Zheng Zhang,<sup>1</sup> and Gang Guo<sup>1</sup> <sup>1</sup>Department of Nuclear Physics, China Institute of Atomic Energy, Beijing 102413, China This paper constructs a multi-layer structural model of GaN HEMT based on Geant4 to simulate the distributions of mass number  $A$ , charge number  $Z$ , kinetic energy  $E_k$ , and linear energy transfer (LET) of secondary particles reaching the GaN sensitive layer after 10 500 MeV protons incident in the gate, source-gate gap, and drain regions. The results indicate that when 10 200 MeV protons are incident on the drain at angles of 0°–60°, the angular effect is smoothed out in the sensitive layer, with deviations in the average  $A$  and  $Z$  less than 10% between angles. This is primarily due to the cumulative attenuation from multiple

Coulomb scattering and energy loss in the overlying layers. Furthermore, vertical irradiations on the gate, source-gate gap, and drain regions with protons of different energies reveal that the gate is most sensitive to energy variations, with the proportion of high-LET ( $> 15 \text{ MeV cm}^2/\text{mg}$ ) events increasing from 5% to 15%, representing a 200% increase in the 10–50 MeV range, attributed to the enhanced nuclear reaction yield by high-Z overlayers; the source-gate gap shows intermediate sensitivity with a change rate of 18%; and the drain is the least sensitive, only obvious increase in high-LET interval. These quantitative patterns reveal the microscopic influences of overlayer materials and geometric structures on secondary particle transport, providing a physical basis for explaining threshold issues such as SEGR and SEB.

Keywords: GaN HEMT, proton radiation, single event effect, high-Z fragment, Geant4 simulation

## INTRODUCTION

GaN high electron mobility transistors (HEMTs) outperform traditional Si devices in high-frequency and high-temperature applications due to their wide band gap, high critical breakdown field, and the high conductivity and excellent thermal stability of the two-dimensional electron gas [1, 2]. Compared to GaAs, GaN has higher thermal conductivity, and makes the overall performance of the device more promising in high-voltage environments [1]. Hence, GaN HEMTs have attracted significant attention for applications in radiation environments such as space electronics, power conversion, and RF front-ends of nuclear power plant [3].

Existing research on non-single-event radiation effects (such as total ionizing dose and displacement damage) has provided representative conclusions at the material and device levels. For example, Ionascut-Nedelcescu et al. systematically evaluated the radiation tolerance of GaN through material and device samples, highlighting its intrinsic hardness advantages under various irradiation and establishing a baseline for device-level assessments [1]. Regarding degradation mechanisms and energy window selection, Liu et al. conducted proton irradiation experiments on AlGaIn/GaN HEMTs with different energies, revealing the sensitivity patterns of DC and RF parameters to proton energy regions under fixed flux, thereby guiding test energy selection and degradation interpretation [3]. In terms of bias and total dose coupling, Jiang et al. compared the worst-case bias conditions under proton and 10-keV X-ray irradiations, noting that substrate and structural differences can lead to different degradation paths and threshold positions, emphasizing the need to \* Supported by CNNC's R&D platform steadily supports scientific research projects (WDZC-2024-056, WDZC-2023-AW-0201); National Natural Science Foundation of China (No. 12405323), and the Fund of Innovation Center for Radiation Application (KFZC2023021201). † E-mail: lili@ciae.ac.cn. combine bias with irradiation to determine degradation limits Research on the sensitivity of GaN HEMTs to single event effects (SEEs) mainly focuses on mechanisms

induced by heavy ions and protons. Kuboyama et al. observed single-event damage in AlGaIn/GaN HEMTs through heavy-ion irradiation experiments, pointing out that regions near the gate and drain are more prone to irreversible failures, emphasizing the decisive role of local device structures in event thresholds [5]. For commercial power devices, Mizuta et al. conducted heavy-ion tests on multiple GaN HEMTs, evaluating the behavior of SEE and potential failure sites below the rated voltages, and noting that the mechanisms of “normally-off” structures require further experimental and theoretical support [6]. Recent reviews and device-level studies indicate that GaN HEMTs are susceptible to issues such as heavy-ion-induced single-event burnout (SEB), single-event gate rupture (SEGR), transient currents, and parasitic channels, which need to be addressed through quantitative energy deposition parameters combined with material structures and event statistics [7]. Additionally, Osheroff et al. systematically characterized the LET and range of proton-induced recoils in GaN, showing that compared to Si, GaN exhibits higher LET limits and larger high-LET interval statistics about 20% higher than Si in higher energy regions, providing numerical references for SEE mechanism studies in proton environments [8]. Proton irradiation studies on GaN-based MIS-HEMTs further emphasize reliability impacts from LET variations [9]. High-Z materials in the upper layers of devices can produce short-range, high-LET ions under proton induction, forming secondary SEE risks. Ladbury et al. proposed an evaluation method based on mission proton spectra and high-Z nuclear reaction cross-sections, combined with metal layer thickness, overlayer dielectrics, and sensitive volume geometry, to calculate equivalent LET distributions, defining destructive and non-destructive SEE risks, and highlighting the weakening effect of overlayers on high-Z fragments [10].

Distinguishing internal recoils from exogenous high-Z fragments is crucial for system-level radiation-hardened design of GaN devices.

Recent experiments have further revealed the specific impacts of proton radiation on GaN HEMT SEEs, for example, Zhang et al. observed a significant reduction in SEB thresholds after proton irradiation (decreasing 15–20% from initial values), attributed to positive charge accumulation and defect-induced parasitic channels [11]. Wang et al. discussed the coupling effects of pre-stress, LET, and gate voltage on SEEs, noting that negative gate voltage can amplify gate sensitivity [12]. Huang et al. analyzed the SEB mechanisms of p-GaN gate HEMTs through experiments and TCAD simulations, emphasizing the amplifying role of buffer layer defects in high-LET events [13]. Wu et al. compared damages from protons and heavy fragments on Cascode GaN HEMTs, quantifying defect density increases from  $3.27 \times 10^{16} \text{ cm}^{-3} \text{ eV}^{-1}$  to  $7.17 \times 10^{16} \text{ cm}^{-3} \text{ eV}^{-1}$ , and discussing threshold degradation under synergistic irradiation [14]. Huang et al. studied degradation mechanisms under synergistic proton and heavy-ion irradiation, revealing the dominant role of proton contributions in secondary particle generation [15].

Although existing literature has accumulated clear experiences in total dose

and displacement damage, research on SEEs in GaN HEMTs lacks a unified microscopic mechanism framework, especially regarding secondary particle transport, energy deposition distributions under proton irradiation, and their spatial differences in gate, source-gate gap, and drain regions. These quantitative data are foundational for interpreting event thresholds and cross-sections, and influence energy-angle testing windows, local structural optimization, and packaging selection. In this study, Geant4 was employed to simulate a multi-layer model of GaN HEMTs, setting analysis windows in the gate, gap region, and drain to obtain the distribution functions of A, Z,  $E_k$ , and LET incident on the GaN sensitive layer; analyzes multi-angle incidences of 10–200 MeV protons, revealing angular effects in the sensitive layer under different proton energies, as well as sensitivity differences caused by irradiations in different regions.

These results provide a physical basis for GaN HEMT SEE mechanism analysis and radiation-hardened design. Compared to existing work, this paper quantifies the characteristics of angular effect attenuation and its energy dependence through regionalized analysis, bridging microscopic particle distributions with device-level SEE threshold degradations.

**II. THEORETICAL BACKGROUND**

**A. Microscopic Mechanisms of Proton on GaN HEMT**

When protons are incident on the multi-layer structure of GaN HEMTs, energy deposition is primarily dominated by electromagnetic interactions and nuclear reactions. The average ionization energy loss can be described by the Bethe-Bloch formula [16]:  $4\pi z^2 e^4 \rho Z \text{mev}^2 A$  (cid:20) (cid:18)  $2\text{mev}^2$  (cid:19)  $I(1 - \beta^2)^{-2} - \beta^2 - \delta$  (cid:21) where  $Z$  is the proton charge number,  $\beta = v/c$  is the relativistic factor,  $I$  is the average excitation energy of the target material, and  $\delta$  is the density effect correction. Energy loss in thin layers follows the Landau-Vavilov distribution [17], exhibiting long-tail characteristics, especially amplifying local energy fluctuations in shallow layers, thereby increasing the probability of threshold events. Angular broadening is dominated by multiple Coulomb scattering, with the root-mean-square scattering angle  $\theta_0$  approximated by the Highland formula [18]:  $\theta_0 \approx 13.6 \text{MeV} \times \frac{1}{p} + 0.038 \ln \left( \frac{p}{X_0} \right)$  (cid:19)(cid:21) (cid:18)  $\times$  where  $p$  is the momentum, and  $X_0$  is the radiation length. Cumulative small-angle scattering dominates directional broadening, making angular effects most significant in shallow layers, with gradual attenuation as layer depth increases.

Elastic and inelastic reactions of protons with Ga and N nuclei produce secondary recoil ions, altering particle composition and LET distributions. Compared to Si, the high atomic number of Ga in GaN ( $Z=31$ ) leads to higher LET limits and shorter ranges for recoil ions, which is the fundamental reason for differences in SEE thresholds between GaN and Si experiences. This study focuses on four observables: average mass number  $\bar{A}$  and charge number  $\bar{Z}$  (representing ion composition), average kinetic energy  $\bar{E}_k$  (determining penetration and track length), and average LET (linking microscopic deposition to SEE thresholds), defined as: (cid:88) (cid:88) (cid:88)  $E_{k,i}, L_{ET} =$

(cid:88) Among them,  $N$  is the total number of particles reaching the analysis window, and is the step-length energy loss of the  $i$ -th particle. These quantities bridge microscopic processes with device effects, providing a quantitative basis for subsequent energy deposition distribution analysis and used in results to evaluate SEE event probabilities.

B. Model and Simulation Calculations Based on a typical GaN HEMT structure, as shown in Figure 1, the model includes an overlayer (280nm Au in gate, and 20 nm Au in drain, density 19.3 g/cm<sup>3</sup>; 50 nm Ni, density 8.9 g/cm<sup>3</sup>), AlGaIn barrier layer (25 nm, density 5.5 g/cm<sup>3</sup>), and 1500 nm GaN layer (density 6.15 g/cm<sup>3</sup>), which is the sensitive volume, with lateral dimensions matching the beam spot (10  $\mu\text{m} \times 10 \mu\text{m}$ ). Analysis regions are located at: 1(cid:13) gate region (restricted by Au/Ni overlayer and AlGaIn barrier); 2(cid:13) source-gate gap region(The stacking sequence is the same as Fig. 1 [Figure 1: see original paper]. Schematic of GaN HEMT Device Structure and Incident Sites. drain-gate region); 3(cid:13) drain region. Simulated incident particles are parallel monoenergetic proton beams, with energy range 10 500 MeV, angles of 0°, 30°, 45°, and 60°, simulating 109 events per condition.

Fig. 2 [Figure 2: see original paper]. Distributions of  $A$ ,  $Z$ ,  $E_k$ , and LET (Normalized Counts  $dN/dX$ ) of Secondary Particles Entering the GaN Sensitive Layer for 10 MeV Protons Incident on the Drain at Different Angles (0°, 30°, 45°, 60°). simulation This work [19]. uses Geant4 Electromagnetic processes calculation employ the G4EmStandardPhysics\_option4 package, including energy loss fluctuations, shell effects, and low-energy electron production, supporting accurate multiple scattering calculations in micron-scale geometries; nuclear reaction processes use the QGSP\_{{BIC}}\_{{HP}} list, suitable for MeV-level nucleon-nucleon interaction reactions, including intranuclear cascade collisions and compound nucleus evaporation [20]. The simulation detector uses G4VSensitiveDetector to record  $A$ ,  $Z$ ,  $E_k$ , and LET for each event at the GaN layer boundary trajectory-restricted energy loss  $dE/dx$ , (calculated as tracking secondary particles with  $E_k > 1$  keV, optimizing computation with electron low-energy cutoff). Data output uses G4AnalysisManager for statistics, with fixed random seeds to ensure reproducibility. Model validation: LET distributions are consistent with Osheroff et al. [8]. These settings ensure the reliability of simulation results, reflecting energy deposition in real device sensitive volumes, complementing experimental SEE thresholds.

III. RESULTS AND DISCUSSION Influence of Incident Angle and Energy on Deposition First, we simulated protons of 10 MeV, 100 MeV, and 200 MeV energies incident on the device drain at different angles, obtaining the distribution functions of mass number  $A$ , charge number  $Z$ , kinetic energy  $E_k$ , and linear energy transfer LET of secondary particles entering the GaN sensitive layer.

Fig.2 to Fig.4 show the distributions of  $A$ ,  $Z$ ,  $E_k$ , and LET under 10 MeV, 100 MeV, and 200 MeV proton energies at different angles, respectively. Because of As shown in the figures, when the incident angle increases, the distribu-

tion functions entering the GaN sensitive layer are consistent in most intervals except for obvious differences in a few, indicating that after protons incident through the drain top, undergoing multiple scattering and energy transfer dissipation, the angular effects on mass number, charge number, energy, and LET values in the sensitive layer are all “smoothed out”. The merging of curves around the LET = 1.9–2.1 MeV cm<sup>2</sup>/mg Fig. 3 [Figure 3: see original paper]. Distributions of A, Z, Ek, and LET (Normalized Counts dN/dX) of Secondary Particles Entering the GaN Sensitive Layer for 100 MeV Protons Incident on the Drain at Different Angles (0°, 30°, 45°, 60°). corresponds to the minimum ionizing particle (MIP) peak, a material-intrinsic feature where most secondary particles exhibit typical energy loss rates; The apparent downward step is a histogram binning artifact (bin width 0.1 MeV cm<sup>2</sup>/mg) enhanced by the logarithmic scale, consistent with the long-tail characteristics of the Landau-Vavilov distribution.

In the figures, when the incident angle increases, the distribution functions entering the GaN sensitive layer are consistent in most intervals, with obvious deviations only in the high-LET tail (> 15 MeV cm<sup>2</sup>/mg), indicating that after protons incident through the drain top, undergoing multiple scattering and energy transfer dissipation, the angular effect is significantly smoothed out in the sensitive layer. Comprehensive analysis shows that at 10 MeV, due to lower proton energy, the average A and Z of secondary particles are minimal (A deviation 9.13% ± 2%, similar for Z), with larger deviations in the high-tail region of the LET spectrum, consistent with the long-tail characteristics of the Landau-Vavilov distribution. As energy increases, the proportion of Z > 20 secondary fragments increases from 15% ± 3% at 10 MeV to 40% ± 5% at 200 MeV, the number of high-LET events increases from 0.2% to 1.2% (a 500% increase), and the maximum LET increases from 15 MeV cm<sup>2</sup>/mg to 18 MeV cm<sup>2</sup>/mg. Table 2 . Comparison of Average Observables in Three Regions under 100 MeV Vertical Incidence. A Z Ek(MeV) LET (MeV · cm<sup>2</sup>/mg) (cid:0) MeV (cid:1) Region Gate 14.2 7.1 Drain 16.8 8.4 Fig. 4 [Figure 4: see original paper]. Distributions of A, Z, Ek, and LET (Normalized Counts dN/dX) of Secondary Particles Entering the GaN Sensitive Layer for 200 MeV Protons Incident on the Drain at Different Angles (0°, 30°, 45°, 60°).

Table 1 . Average Mass Number A and Charge Number Z of Secondary Fragments Entering the Sensitive Layer for Protons of 10 MeV, 100 MeV, and 200 MeV Incident on the Drain at Different Angles

**200 MeV 0.827 0.313 0.826 0.311 0.824 0.311 0.822 0.309**

MeV cm<sup>2</sup>/mg, which a 20% increase. This trend arises from the increase in proton nuclear reaction cross-sections with energy, consistent with the recoil ion LET limits in GaN, Where 20% higher than Si.

B. Regional Comparative Analysis The 3 typical region comparison shows that the gate tends toward low-E<sub>k</sub> and low-Z distributions under low-energy (10 50 MeV) conditions, for example, average E<sub>k</sub> of 35 MeV ± 4 MeV (20% lower than the drain), average Z of 7.1 ± 0.7, due to filtering restrictions from the Au/Ni over-layer and AlGa<sub>0.5</sub>N barrier, leading to more significant shallow-layer energy loss, consistent with the Z/A dependence in the Bethe-Bloch formula (1). At 10 MeV, the proportion of high-LET events at the gate is only 3% ± 1%, reflecting the energy screening effect of the overlayer. In contrast, the drain has a larger proportion of high-LET events (increase from 10–3 to 1.25 × 10–3, 25% higher than the gate), benefiting from open geometry allowing more high-Z recoils to penetrate, with average Z of 8.4 ± 0.9 and 15% higher standard deviation in E<sub>k</sub> distribution. The gap region is intermediate, most sensitive to angle changes but with the fastest attenuation, which converges 300 nm, with LET peak between those of the gate and drain, which about 12 MeV cm<sup>2</sup>/mg.

Table 2 summarizes the average observables in the three regions under 100 MeV vertical incidence. These differences quantify the “gating” effect of overlayer filtering strength on particle composition, highlighting spatial non-uniformity of Fig. 5 [Figure 5: see original paper]. Variations of Average A, Z, E<sub>k</sub> (MeV), and LET (MeV cm<sup>2</sup>/mg) with Energy for 10 500 MeV Protons Vertically Irradiating the Gate Region. regionalized sensitivity compared to overall GaN LET spectra in literature [8], providing microscopic evidence for explaining gate-prone failures such as SEGR.

As shown in Fig. 5 to Fig. 7 [Figure 7: see original paper], as the energy increases, the changes in the four physical quantities across the three regions exhibit differences in sensitivity. The gate is the most sensitive. In the 10 50 MeV range, the average A increases from 14.0 to 15.0, which 7%, the average Z from 7.0 to 7.5, which 7% increase, the average E<sub>k</sub> from 35 MeV to 45 MeV, which 29% increase, the maximum LET value decreases from

**18 MeV cm<sup>2</sup>/mg to 15 MeV cm<sup>2</sup>/mg, which 17% decrease,**

and the proportion of high-LET intervals increases from 5% to 15%, representing a 200% relative increase. The source- In the 50 200 MeV range, the gate gap is intermediate. changes are similar but with an 18% lower rate and a 22% increase. The drain is the least sensitive. In the 10 50 MeV range, the changes are minimal, with a 4% increase and a 10% decrease; obvious changes occur above 100 MeV, with the high-LET proportion increasing from 8% to 25%. These differences stem from variations in the top materials and layer counts across the regions, affecting the penetration of secondary fragments [20].

C. Discussion The simulation results reveal that the flattening of the angular effect originates from the accumulation of multiple Coulomb scattering (Equation 2), which dominates in thick overlayers and leads to an attenuation of angle dependence exceeding 90% at the depths of the sensitive layer. The enhancement of high-Z fragments and high-LET events with in-0204010-910-510-1dN/dXA200 MeV(a)1020Z(b)(b)50100Ek(MeV)(c) 0 Degree 30 Degree 45 Degree 60 Degree110LET(MeV · cm<sup>2</sup>/mg)(d)0204010-910-510-1dN/dXAGate(a)1020Z(b)50100Ek(MeV) 10 MeV 50 MeV 100 MeV 200 MeV 300 MeV 400 MeV 500 MeV(c)110LET(MeV · cm<sup>2</sup>/mg)(d)

5 mechanisms in p-GaN gate structures [7, 13]; the open geometry of the drain allows for broader distributions, matching the absence of SEB observations in Cascode GaN HEMT experiments [15]. These microscopic insights bridge simulations and experiments, providing a foundation for SEE probability assessments, such as using the proportion of high-LET events to predict threshold degradations [13]. Limitations include the omission of bias electric fields; future work could integrate TCAD simulations to investigate the impact of field-enhanced charge collection on SEB/SEGR.

IV. CONCLUSIONS This paper quantifies the microscopic mechanisms of proton-induced single event effects (SEEs) in GaN HEMTs through Geant4 simulations. The simulation results indicate that angular effects are significantly smoothed out in the sensitive layer, with attenuation rates inversely proportional to energy, mainly due to the cumulative effects of multiple Coulomb scattering, resulting in secondary particle distribution differences less than 10%. Energy increase enhances the proportion of high-Z secondary fragments ( $Z > 20$ ) and the number of high-LET events, for example, in the drain region, from 10 MeV to 200 MeV, the proportion of high-Z fragments increases from 15% to 40%, and high-LET events increase by 500%, reflecting the amplifying effect of increasing nuclear reaction cross-sections on energy deposition.

Differences in proton incidences across regions further reveal that overlayer materials and geometric structures dominate sensitivity: The Gate is most sensitive to proton energy changes, where, high-LET event proportion increasing of 200%, due to high-Z overlayers screening low-energy particles and amplifying high-energy region recoil ion yields; the source-gate gap is intermediate; the drain is least sensitive, benefiting from open paths allowing broader particle distributions. These microscopic patterns bridge particle transport with device-level SEE threshold degradations, for example, high-LET peaks of gate can explain SEB threshold reductions under proton irradiation. Compared to existing work [15], this paper's regionalized quantification highlights the key role of overlayers in proton-induced SEEs, providing a physical basis for GaN HEMT radiation-hardened design, such as optimizing gate overlayers to alleviate energy sensitivity or adjusting buffer layer thickness to suppress high-LET events.

Future work can integrate bias electric field simulations to explore coupling

effects on SEB/SEGR. transistors, *J. Vac. Sci. Technol. B*, vol. 31, no. 2, p. 022201, Mar. 2013, DOI: 10.1116/1.4788904. [4] Rong Jiang, En Xia Zhang, Michael W. McCurdy et al., Worst- Case Bias for Proton and 10-keV X-Ray Irradiation of AlGaIn/- GaN HEMTs, *IEEE Trans. Nucl. Sci.*, vol. 64, no. 1, pp. 218- 225, Jan. 2017, DOI: 10.1109/TNS.2016.2626962. [5] Satoshi Kuboyama, Akifumi Maru, Hiroyuki Shindou et al., Single-Event Damages Caused by Heavy Ions Observed in Al- GaN/GaN HEMTs, *IEEE Trans. Nucl. Sci.*, vol. 58, no. 6, pp. 2734-2738, Dec. 2011, DOI: 10.1109/TNS.2011.2172464.

Fig. 6 [Figure 6: see original paper]. Variations of Average A, Z, Ek (MeV), and LET (MeV cm<sup>2</sup>/mg) Values with Energy for 10 500 MeV Protons Vertically Irradiating the Source-Gate Gap Region.

Variations of Average A, Z, Ek (MeV), and LET Fig. 7. (MeV cm<sup>2</sup>/mg) with Energy for 10 500 MeV Protons Vertically Irradiating the Drain Region. Increasing energy is associated with the rise in nuclear reaction cross-sections, which explains the reduction in SEB thresholds under proton irradiation (such as a 15-20% decline reported by Zhang et al.[11]), as the high-LET peaks at the gate exceed the SEGR thresholds, 20 30 MeV cm<sup>2</sup>/mg. The regional differences quantify the filtering strength of the overlayers: the energy screening at the gate amplifies high-LET recoils in the high-energy region, consistent with the SEB [1] A. Ionascut-Nedelcescu, C. Carlone, A. Houdayer et al., Radiation hardness of gallium nitride, *IEEE Trans. Nucl. Sci.*, vol. 49, no. 6, pp. 2733-2738, Dec. 2002, DOI: 10.1109/TNS.2002.805363.

[2] Xinwen Hu, B.K. Choi, H.J. Barnaby et al., The energy dependence of proton-induced degradation in AlGaIn/GaN high electron mobility transistors, *IEEE Trans. Nucl. Sci.*, vol. 51, no. 1, pp. 293-297, Apr. 2004, DOI: 10.1109/TNS.2004.824927. [3] Lu Liu, Chien-Fong Lo, Yuyin Xi et al., Dependence on proton energy of degradation of AlGaIn/GaN high electron mobility 0204010-910-510-1dN/dXAGap(a)1020Z(b)50100Ek(MeV) 10 MeV 50 MeV 100 MeV 200 MeV 300 MeV 400 MeV 500 MeV(c)110LET(MeV · cm<sup>2</sup>/mg)(d)0204010-910-510-1dN/dXADrain(a)1020Z(b)50100Ek(MeV) 10 MeV 50 MeV 100 MeV 200 MeV 300 MeV 400 MeV 500 MeV(c)110LET(MeV · cm<sup>2</sup>/mg)(d)

6 [6] E. Mizuta, S. Kuboyama, Y. Nakada et al., Single-Event Damage Observed in GaN-on-Si HEMTs for Power Control Applications, *IEEE Trans. Nucl. Sci.*, vol. 65, no. 8, pp. 1956-1963, Aug. 2018, DOI: 10.1109/TNS.2018.2828421. [7] S. Singha, M.M. Hossain, Numerical Analysis of Single Event Transient Effects in Enhancement-Mode p-GaN/AlGaIn/GaN High Electron Mobility Transistors, *Int. J. Numer. Model. Electron. Networks Devices Fields*, vol. 38, no. 2, p. e3200, Jul. 2025, DOI: 10.1142/S0129156426400094. [8] J.M. Osheroff, J.-M. Lauenstein, R.L. Ladbury, LET and Range Characteristics of Proton Recoil Ions in Gallium Nitride (GaN), *IEEE Trans. Nucl. Sci.*, vol. 68, no. 5, pp. 597-602, May 2021, DOI: 10.1109/TNS.2021.3050980. [9] Zixin Zhen, Chun Feng, Hongling Xiao et al., Proton- Irradiation Effects and Reliability on GaN-Based MIS- HEMTs,

- Micromachines, vol. 15, no. 9, 2024, DOI: 10.3390/mi15091091. [10] Raymond Ladbury, Risk Methodology for SEE Caused by Proton-Induced Fission of High-Z Materials in Microelectronic Packaging, IEEE Trans. Nucl. Sci., vol. 67, no. 6, pp. 1152- 1160, Jun. 2020, DOI: 10.1109/TNS.2020.2993600. [11] Xin Zhang, Hao Huang, Biao Sun et al., Study on Single Event Effects of Enhanced GaN HEMT Devices under Various Con- ditions, Micromachines, vol. 15, no. 8, p. 950, Jul. 2024, DOI: 10.3390/mi15080950. [12] Xiaohu Wang, Chenglong He, Fei Cao et al., Study on the single-event burnout mechanism of p-GaN gate AlGaIn/GaN HEMTs, Appl. Phys. Lett., vol. 124, no. 17, p. 173502, Apr. 2024, DOI: 10.1063/5.0190614. [13] Hao Huang, Ying Wang, Chenglong He et al., Study of Single Event Effect Failure Mechanism in P-GaN HEMTs Based on Experimental and TCAD Simulation, Radiat. Phys. Chem., vol. 232, p. 112698, Mar. 2025, DOI: 10.1016/j.radphyschem.2025.112698. [14] Zhipeng Wu, Huixiang Huang, Jianqun Yang et al., Compar- ative Study of Proton and Heavy Ion-induced Damages for GaN-based HEMTs, in Proc. 8th Int. Conf. Reliab. Syst. Eng. (ICRSE), Beijing, China, Feb. 2025, pp. 1-6.(Published in Proc. ICRSE 2025; available at scholar.hit.edu.cn) [15] Huixiang Huang, Zhipeng Wu, Jianqun Yang et al., Compre- hensive Study of Proton and Heavy Ion-Induced Damages for Cascode GaN-Based HEMTs, Electronics, vol. 14, no. 13, p. 2653, Jun. 2025, DOI: 10.3390/electronics14132653. [16] Hans Bethe, Zur Theorie des Durchgangs schneller Korpusku- larstrahlen durch Materie, Annalen der Physik, vol. 397, no. 3, pp. 325-400, 1930, DOI: 10.1002/andp.19303970303. [17] Lev Landau, On the energy loss of fast particles by ionization, J. Phys. (USSR), vol. 8, pp. 201-205, 1944. [18] V. L. Highland, Some practical remarks on multiple scattering, Nucl. Instrum. Methods, vol. 129, no. 2, pp. 497-499, 1975, DOI: 10.1016/0029-554X(75)90743-0. [19] Geant4 Collaboration, Geant4-a simulation toolkit, Nucl. In- strum. Methods Phys. Res. A, vol. 506, no. 3, pp. 250-303, Jun. 2003, DOI: 10.1016/S0168-9002(03)01368-8. [20] J. Apostolakis, M. Asai, A.G. Bogdanov et al., Geometry and physics of the Geant4 toolkit for high and medium energy ap- plications, Radiat. Phys. Chem., vol. 78, no. 10, pp. 859-873, Oct. 2009, DOI: 10.1016/j.radphyschem.2009.04.026.

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